

OFFICIAL**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Kouchi Nagai et al.**RECEIVED
CENTRAL FAX CENTER**

Confirmation Number: 4556

Serial No.: 09/815,282

JUN 01 2004

Group Art Unit: 2881

Filed: March 23, 2001

Examiner: Paul Gurzo

For: **SCANNING ELECTRON MICROSCOPE
AND METHOD OF CONTROLLING THE SAME**

Attorney Docket: 010391

AMENDMENTCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450Date: June 1, 2004
(TUESDAY AFTER HOLIDAY)

Sir:

This paper is in response to the Office Action mailed on January 30, 2004. Please charge a *one-month* extension fee to Deposit Account No. 01-2340. Any additional fees needed in connection with this paper may be charged to the same number.

A personal interview was conducted on Thursday, May 27. As discussed, the Applicants now formally submit the amendments proposed in draft earlier, and also summarize their arguments from the discussion at the interview in the Remarks below (which comprise the Applicants' required summary of the substance of the interview).

The phrase "fixed scanning range" in claim 1 is supported in the specification at page 13, line 3; it corresponds to the "second scanning range FOV2" recited in claims 9 and 20. Also, a "constant" scanning range is recited at page 6, line 36, and page 9, line 19 states that the capturing of secondary electrons is done "without changing the scanning range in one direction at a high magnification." The scanning direction over a fixed scanning range is further supported at page 6, lines 1-7. The word "length" is supported at page 14, line 26. The object "surface" is supported at page 6, line 33.